

Title (en)

ADHERED SUBSTANCE REMOVING METHOD AND FILM-FORMING METHOD

Title (de)

VERFAHREN ZUR ENTFERNUNG VON HAFTENDEN STOFFEN UND FILMBILDUNGSVERFAHREN

Title (fr)

PROCÉDÉ D'ÉLIMINATION DE SUBSTANCE COLLÉE ET PROCÉDÉ FILMOGÈNE

Publication

EP 4060076 A1 20220921 (EN)

Application

EP 20888253 A 20201104

Priority

- JP 2019204954 A 20191112
- JP 2020041239 W 20201104

Abstract (en)

Provided are a deposit removal method and a film deposition method capable of removing a selenium-containing deposit adhering to an inner surface of a chamber or an inner surface of piping connected to the chamber without disassembling the chamber. A selenium-containing deposit adhering to at least one of the inner surface of a chamber (10) or the inner surface of exhaust piping (15) connected to the chamber (10) is removed by reacting with a cleaning gas containing a hydrogen-containing compound gas.

IPC 8 full level

C23C 16/44 (2006.01); **H01L 21/205** (2006.01)

CPC (source: CN EP IL KR US)

C23C 16/305 (2013.01 - EP KR); **C23C 16/44** (2013.01 - CN IL); **C23C 16/4405** (2013.01 - CN EP KR US); **H01L 21/02175** (2013.01 - US); **H01L 21/02568** (2013.01 - KR); **H01L 21/205** (2022.08 - IL)

Designated contracting state (EPC)

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Designated extension state (EPC)

BA ME

DOCDB simple family (publication)

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